MOOV

1. **Equipment & Model :** LAM AutoEtch Plasma Etching System

2. **Manufacturer :** LAM

3. **Delivery Date :**
Delivery on about 4 weeks after PO

4. **Wafer Size : 6 inch** , 150mm

6. **Process (Product) : Oxide Etch but it can be converted to Poly / Nitride**

7. **Hardware Configuration**
   - High throughput , Vacuum Lodad-Locked
   - Fully automated Microprocessor Control
   - ENI OEM-6 generator (13.56MHz, 650Watt)
   - M&W Chiller
   - Standard Pneumatic Loader Mechanism
   - 208 V 3 Phase, 60 Hz
   - Pumps for Process Chamber & Loadlock
     Alcatel Pump with Booster Pump

Foot Print

Main Body : H:1397mm W:1117mm D:1108mm